

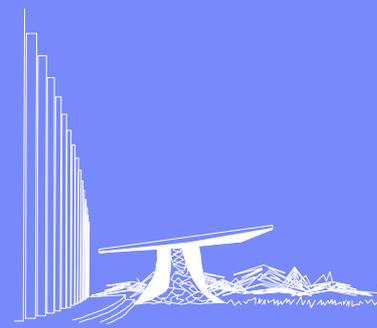


IBM Research

# On SOI CMOS as Technology Platform for SoC and Hybrid Device and Function Integration

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Tokyo Institute of Technology, Tokyo, Japan

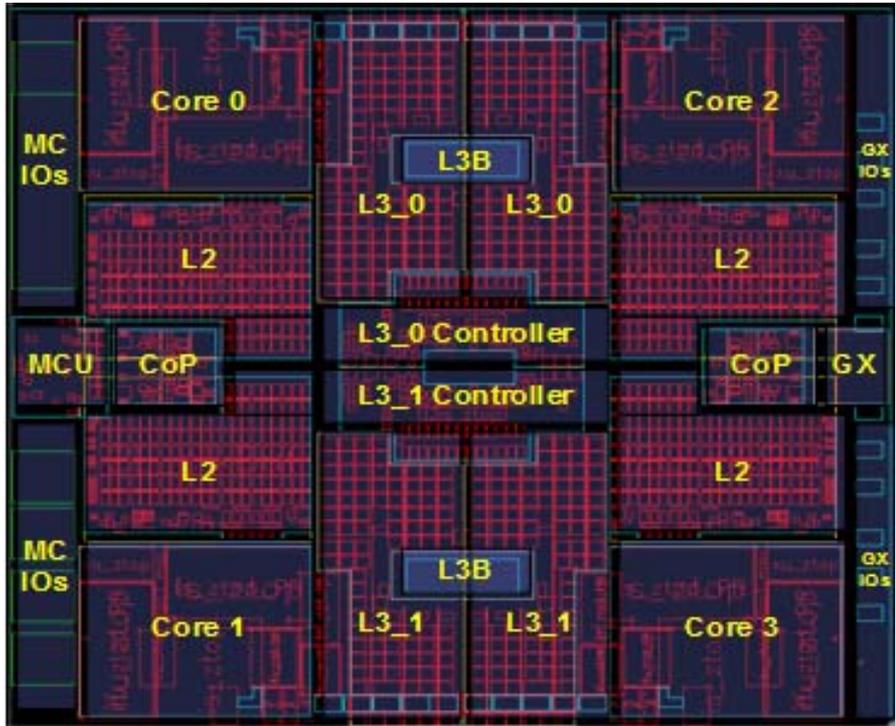


# Outline

- **CMOS Platforms**
  - Bulk silicon
  - Silicon on insulator (SOI)
- **Considerations for SoC Functions and Embedded Hybrid Devices**
- **Examples of SOI-Enabled Embedded Devices and Functions**
- **Summary**

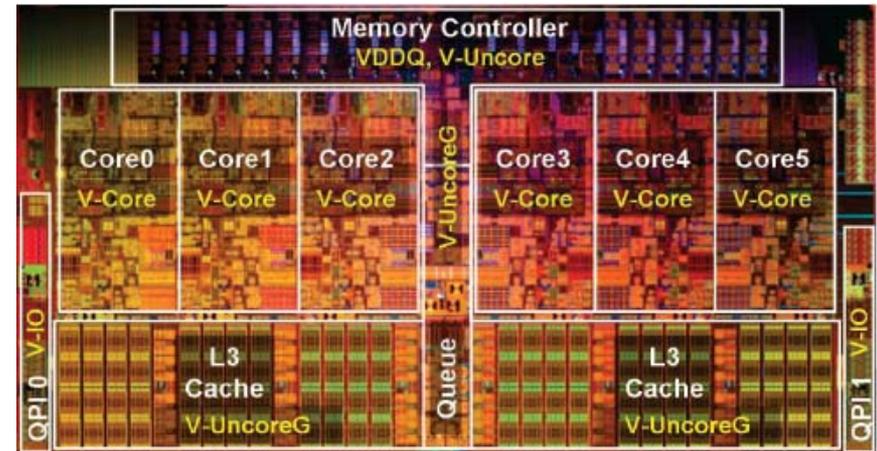
# CMOS in Systems Today

## SOI CMOS



IBM's 45 nm 4-core 5.2GHz z196

## Bulk Silicon CMOS



Intel's 32 nm 6-core Westmere

# A 45SOI vs. 45LP CMOS Design Comparison

## Conclusion

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- ARM1176 design and silicon implementation with standard commercial EDA flow using SOI physical IP
  - Standard cell library
  - Single-port SRAM compiler
  - GPIO
  - PLL
- Silicon demonstration of high-performance and low-power capability of 45SOI vs 45LP
  - 40% power reduction at 500MHz
  - 20% higher speed with still 28% power reduction
  - 1GHz achievable with same implementation
  - Static power reduction at room temperature may be achieved with power management techniques

# System-on-Chip and Hybrid Integration

- **Why?**
  - The ultimate goal in **INTEGRATED-CIRCUIT** technology
  - Higher performance and/or lower power dissipation, ideally at lower cost
- **What devices and functions to integrate?**
  - Integration of CPU and cache memory already routine
  - Devices and functions to be developed and integrated on chip
    - ➔ whatever the system designers need to deliver winning products to their customers

# What Devices and Functions to Integrate, and How?

## ■ What?

- **From TSMC website:** “No longer is a logic focused process technology able to meet all market requirements. Rather, today's industry innovator requires special feature technologies such as mixed-signal/RF, embedded high density memory, non-volatile memory, high voltage devices and CMOS image sensor technologies.”

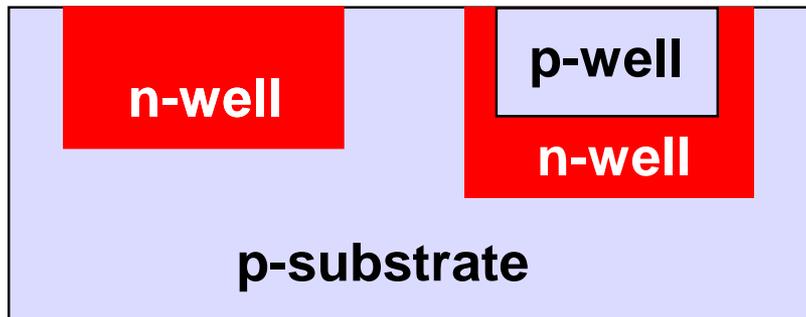
## ■ How?

- Integrate these and other devices and functions, as many as reasonable from a **system product cost, performance, and power dissipation perspective**

# Electrical Isolation – a Major Challenge in Integration

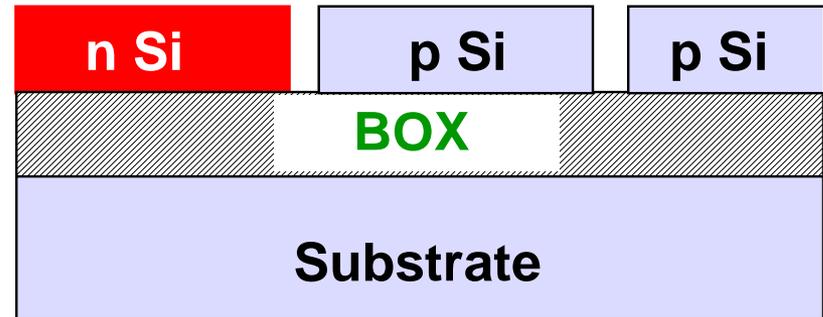
## ▪ Bulk silicon CMOS

- Isolation by doped well regions
- Large area
- Large parasitic capacitance
- Less complete isolation; isolation noise

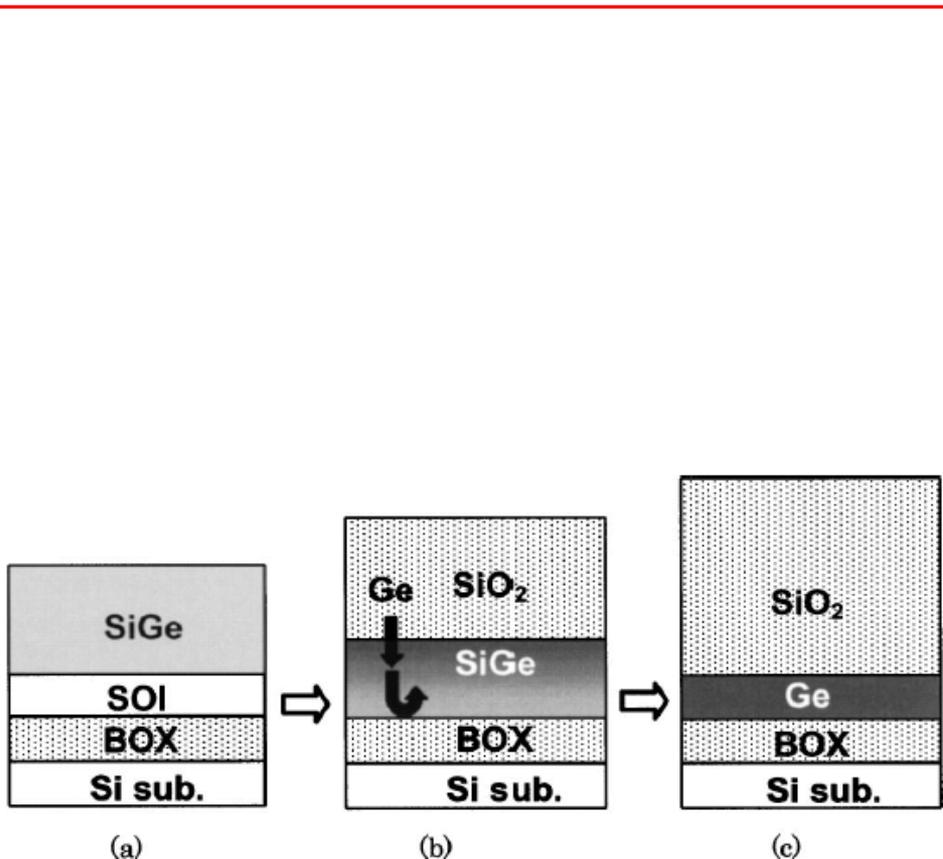


## ▪ SOI CMOS

- Isolation by BOX and oxide filled shallow trenches
- Isolation feature size small and scalable
- Small parasitic capacitance
- Isolation noise can be small; especially with “substrate” engineering

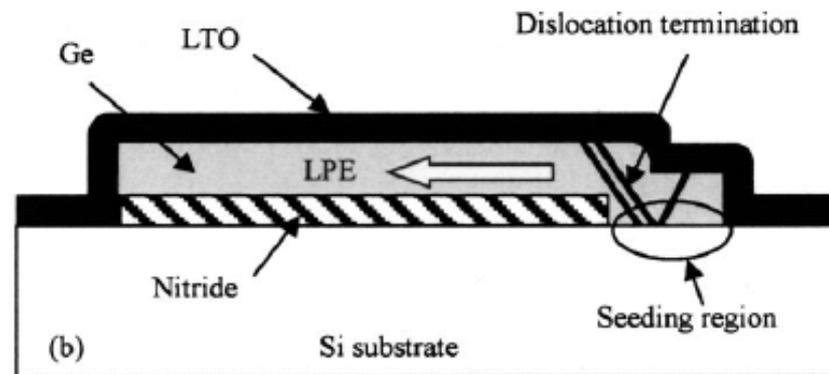
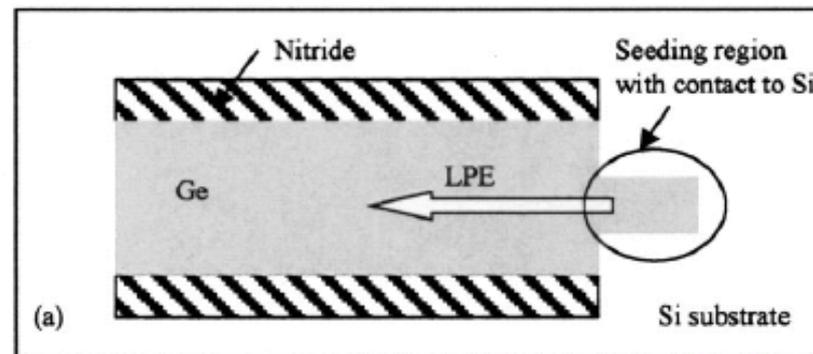


# Ge on Insulator



**Ge condensation by oxidation**

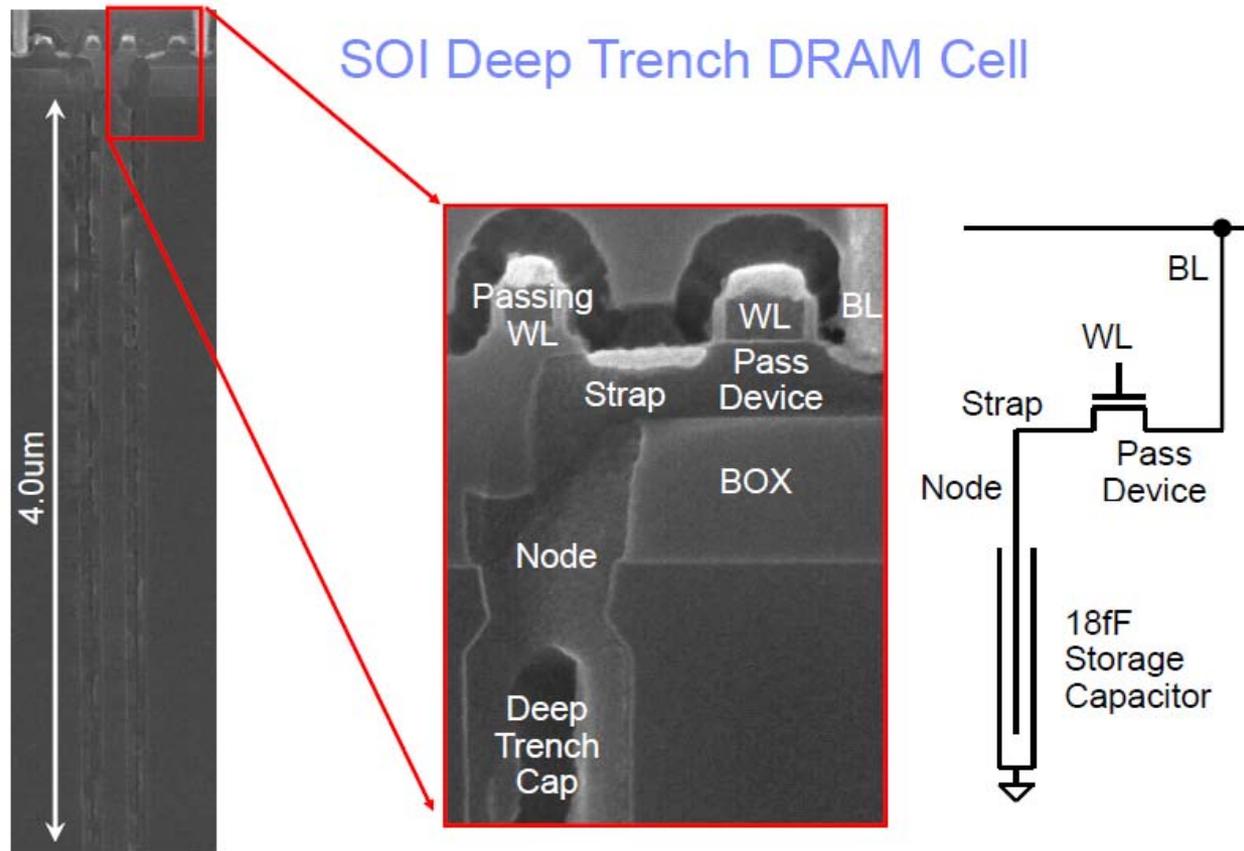
*Ref: S. Nakaharai et al., APL vol. 83, p. 3516 (2003)*



**Growth by liquid phase epitaxy**

*Ref: Y. Liu et al., APL vol. 84, p. 2563 (2004)*

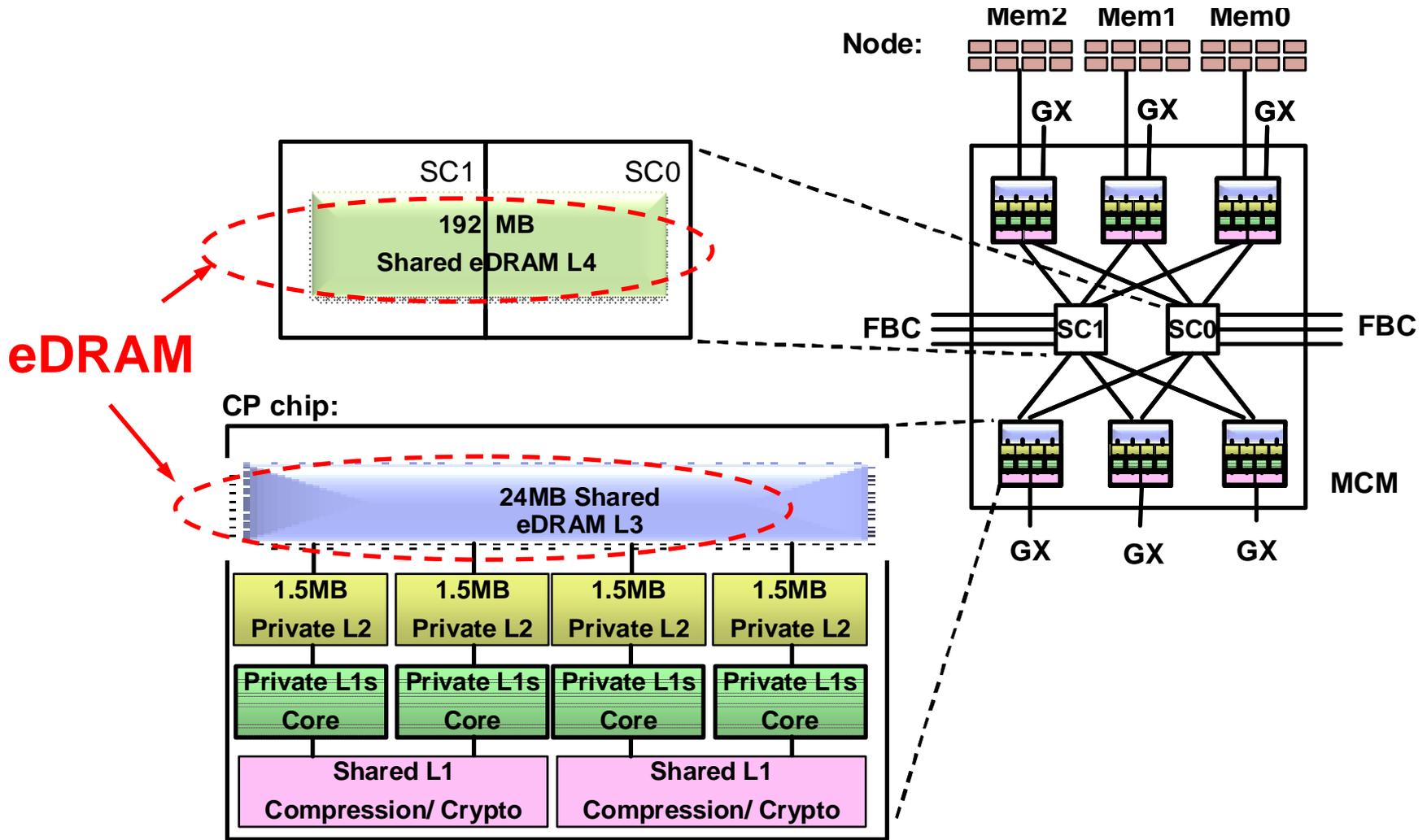
# eDRAM in High-Performance SOI Microprocessors



- 45nm SOI processors for IBM's Power7 servers and z196 mainframes

Reference: J. Barth et al., 2010 ISSCC

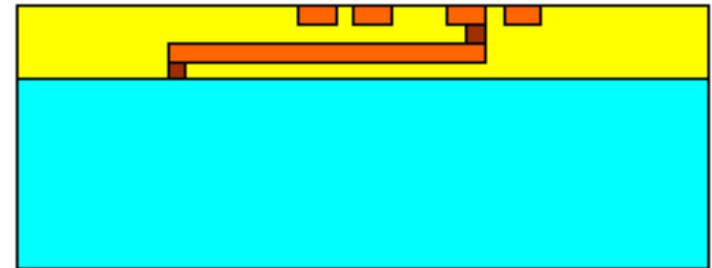
# Z196 (IBM Mainframe) Cache / Node Topology



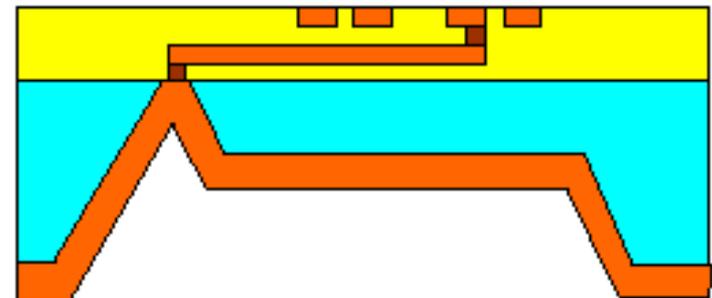
Source: B. Curran, HOT CHIP Conference, Aug. 21, 2010

# Substrate Engineering for RF

- SOI substrate can be engineered to meet system requirement
  - High resistivity
  - Patterned doped regions
  - Etched and/or processed
  - ...



• after RF/IC process

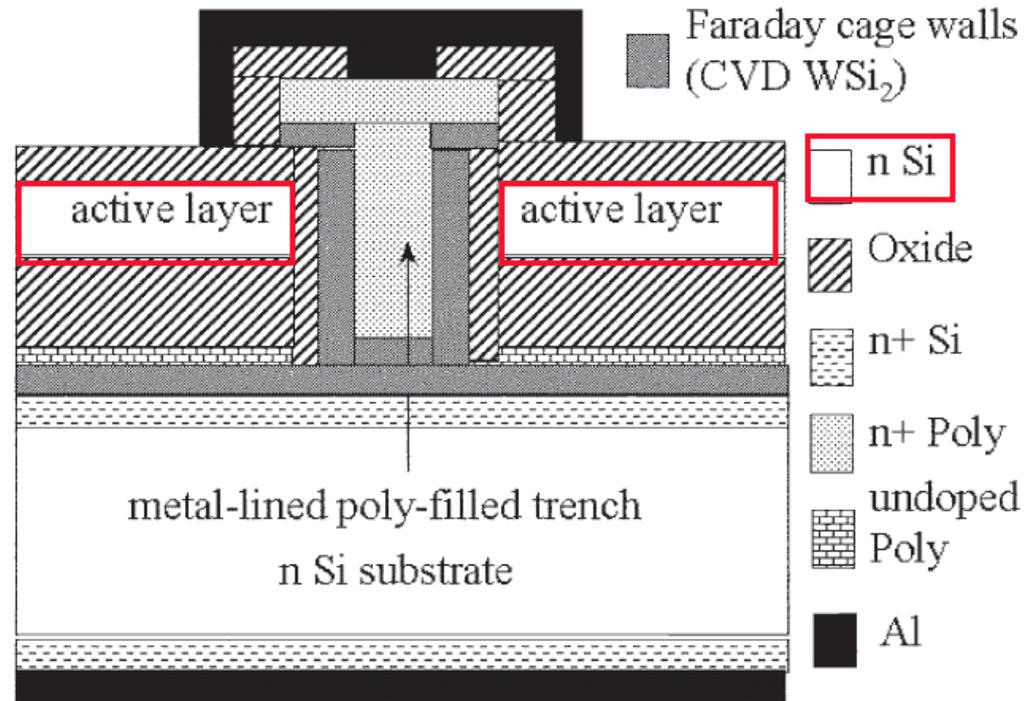


• after post-processing

Reference: J. Burghartz et al., 2002 BCTM

# Substrate Engineering for Crosstalk Reduction

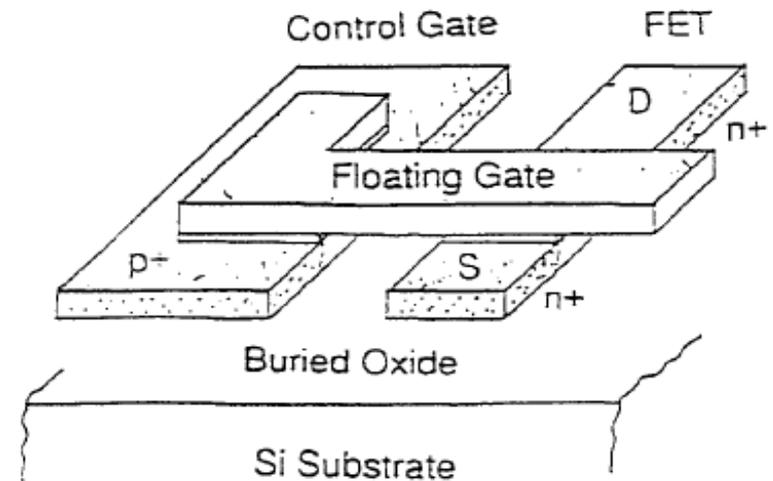
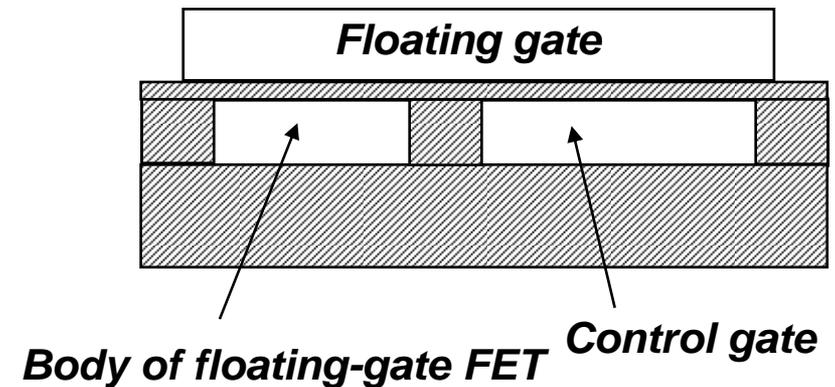
- Ground-plane with Faraday cage
  - “Over ten times reduction in crosstalk is demonstrated up to 10 GHz, compared to previously reported substrate crosstalk suppression technologies.”



Reference: S. Stefanou et. al., *IEEE TED*, p. 486 (2004)

# Single-Poly Embedded EEPROM in SOI

- Silicon body layer used as control gate
- Only requirement is a thick  $T_{ox}$  for floating-gate operation



*References: Acovic, Ning and Solomon, US Patent 5,886,376;  
Solomon and Su, 15<sup>th</sup> IEEE NVRAM Workshop, paper 4.2, 1997.*

# Single-Poly Embedded EEPROM in SOI

- Experimental data based on SOI CMOS with  $T_{ox} = 4.5$  nm

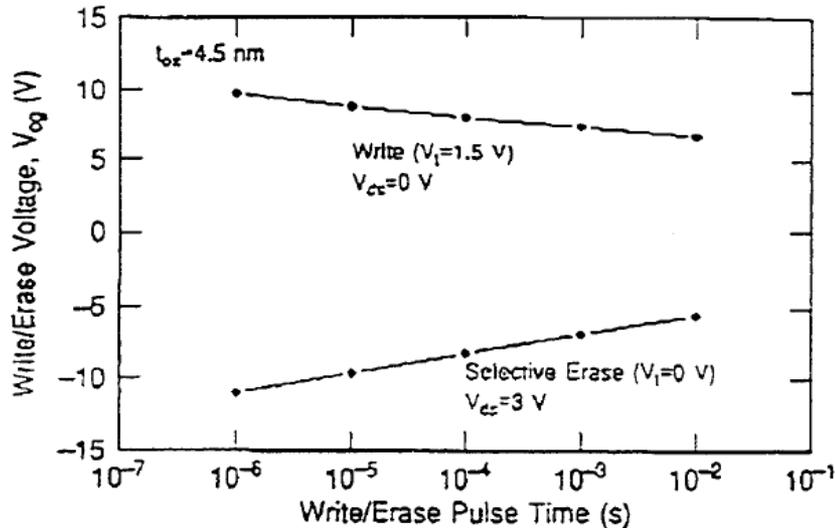


Figure 5. Write/erase threshold voltage vs. pulse time.

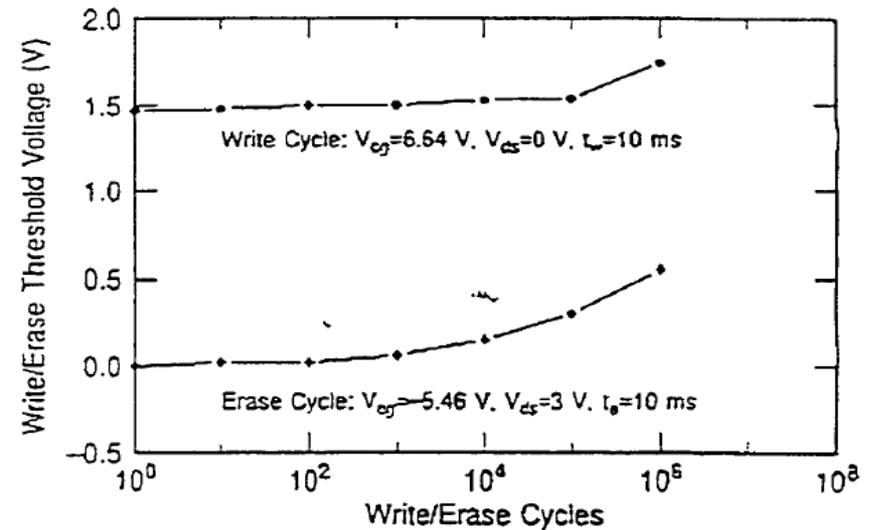
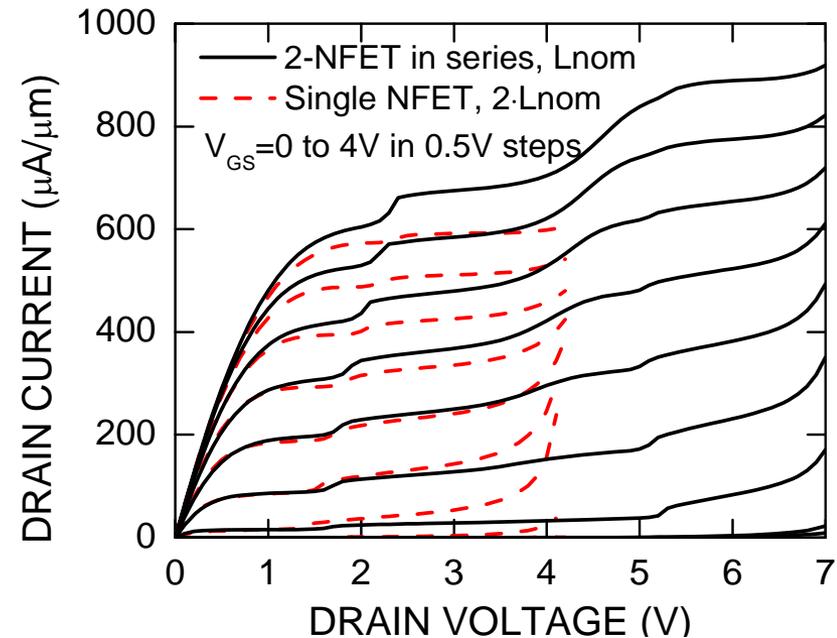
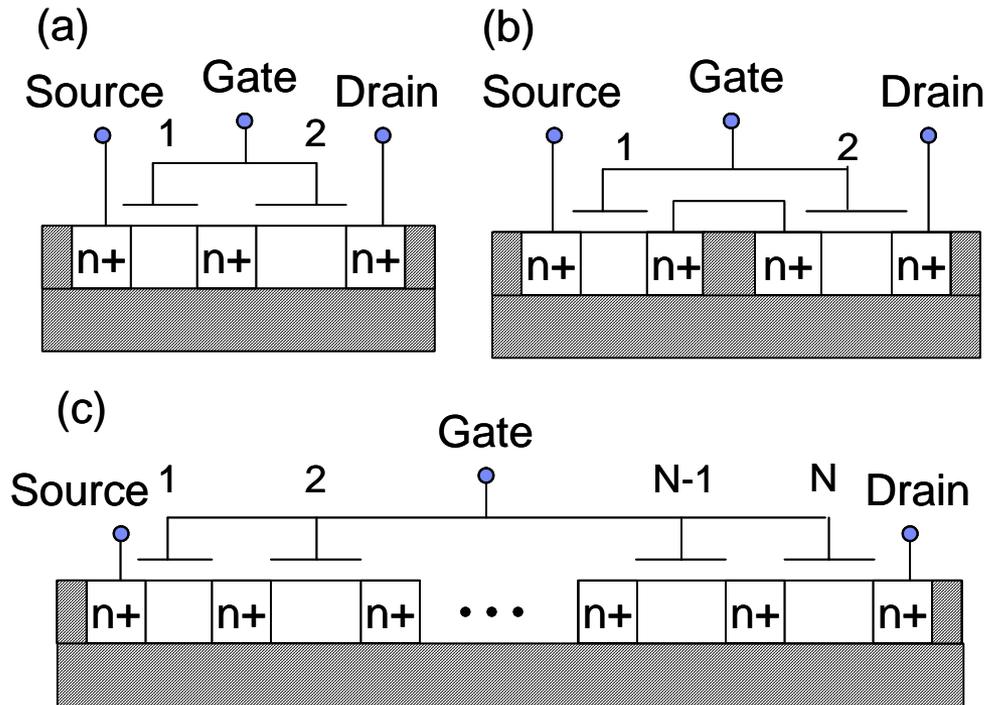


Figure 6. Write/erase threshold voltage vs. number of cycles.

References: Solomon and Su, 15th IEEE NVRAM Workshop, paper 4.2, 1997.

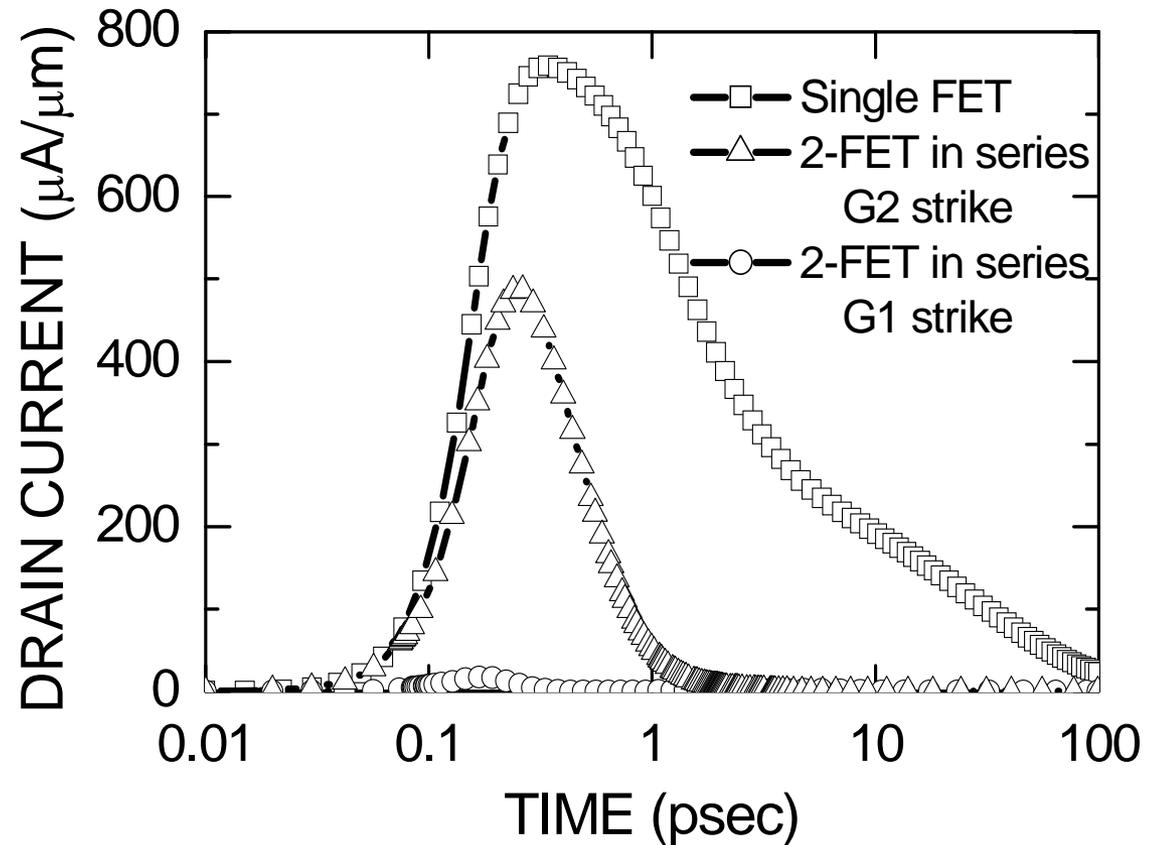
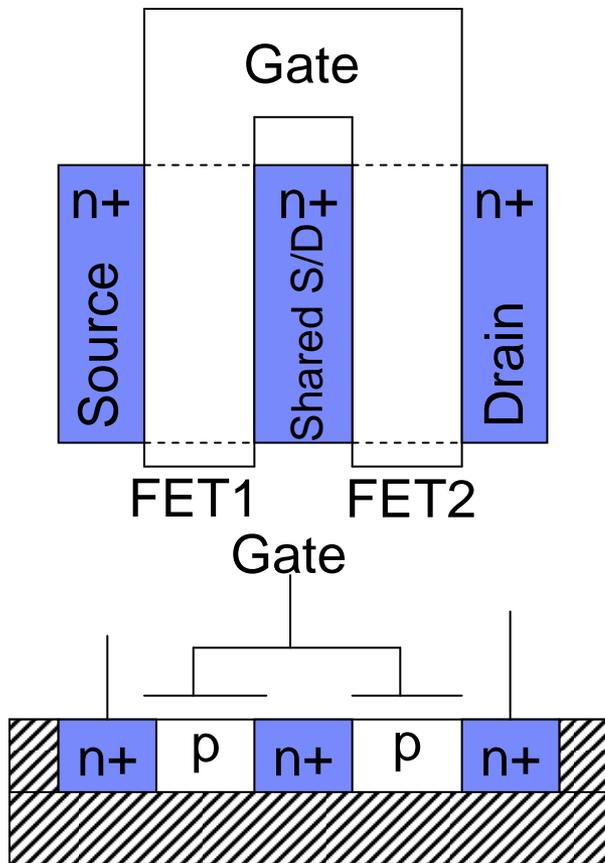
# SOI Series-Connected (Stacked) FETs



- Stacked device for high voltage and for soft-error immunity

Reference: J. Cai et al., 2008 IEEE Int. SOI Conference, pp. 21-22

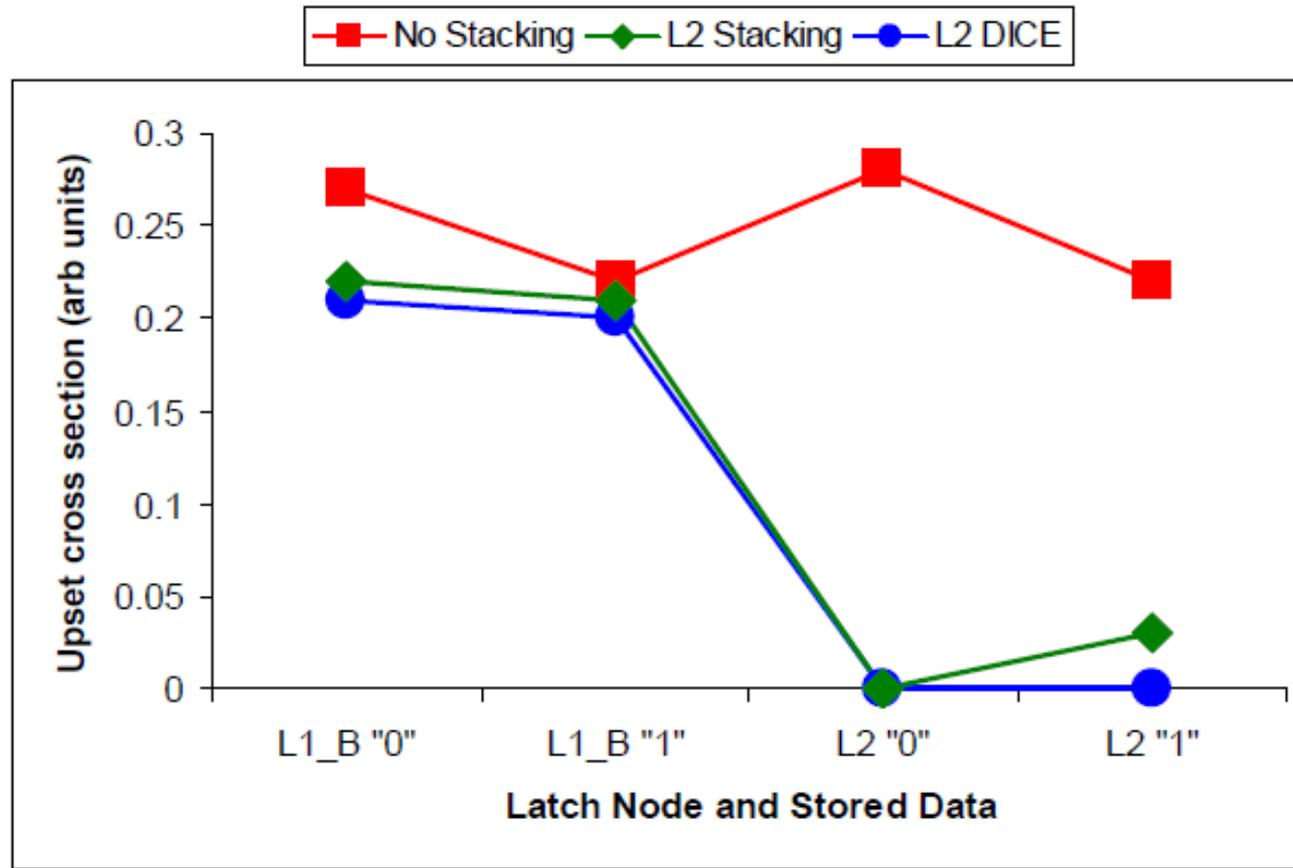
# Stacked SOI Device for SEU Immunity



Reference: J. Cai et al., 2008 IEEE Int. SOI Conference, pp. 21-22

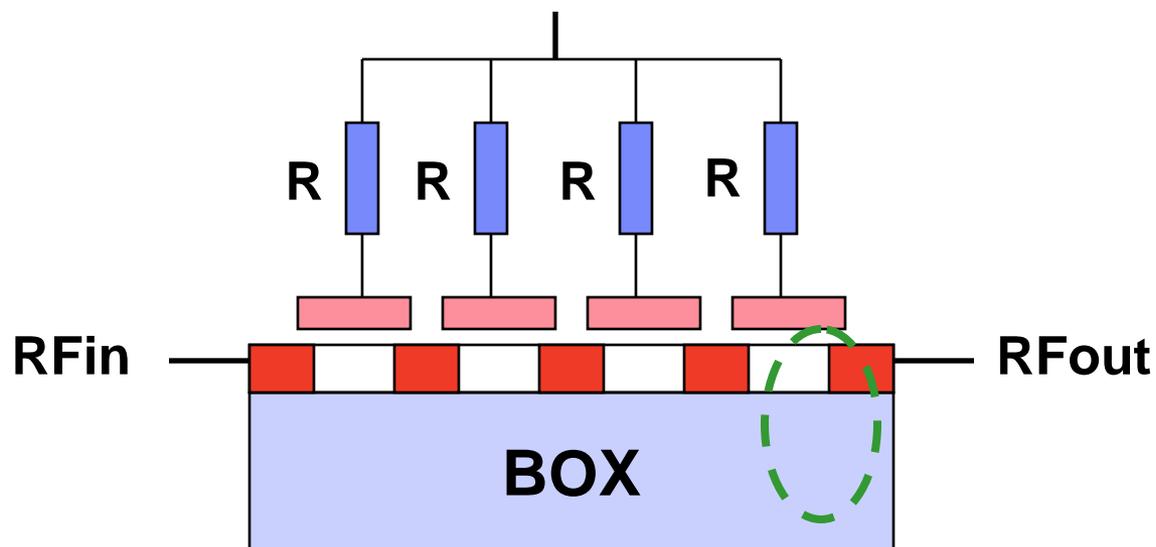
# Latches Employing Stacked SOI Device as Effective as Dual Interlock Cell (DICE) Latches for SEU

## Upset Cross Sections (SOI designs)



Reference: J. Warnock et al, 2010 ISSCC

# High-Voltage SOI FET RF Switch



**No diffusion-to-substrate breakdown**

# SiGe-CBiCMOS on Thick SOI

- Thick SOI with high resistivity substrate; deep and shallow trench isolation
- Vertical SiGe npn and pnp
- 3.3V and 2.5V CMOS

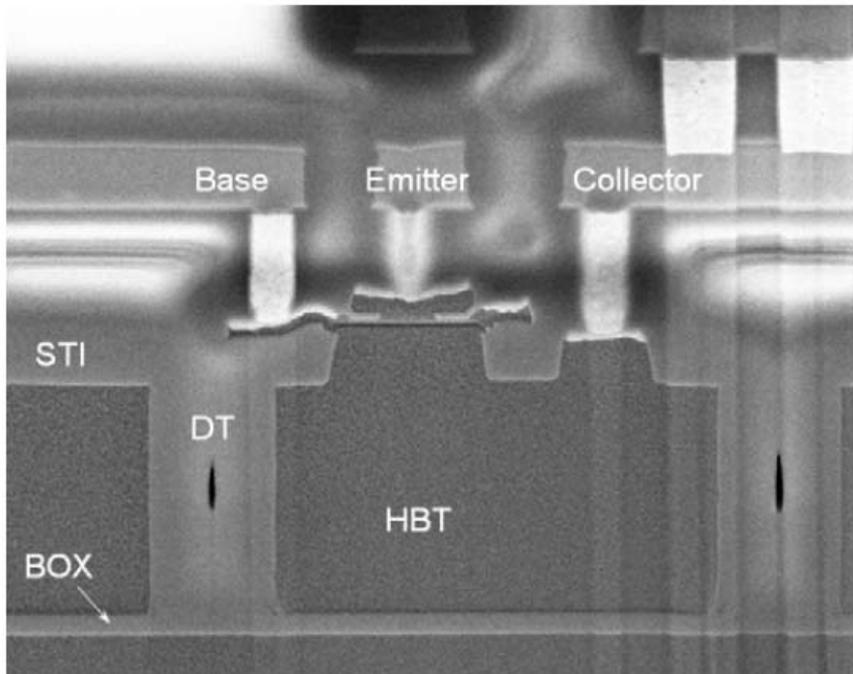


Fig. 2. SEM X-section showing an HBT with DT/STI isolation on SOI.

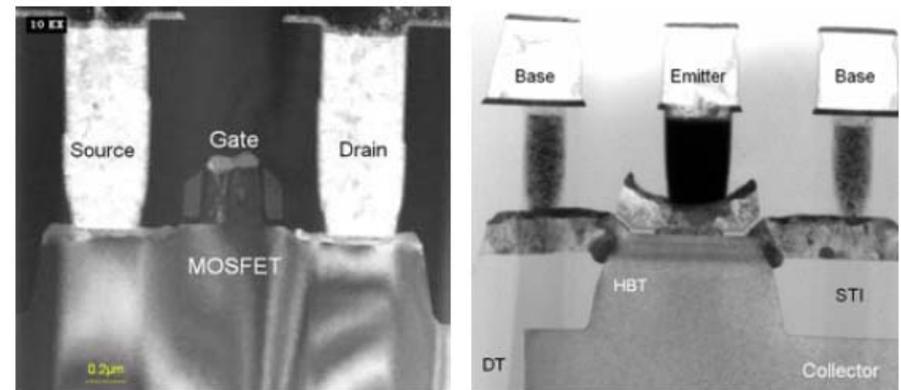
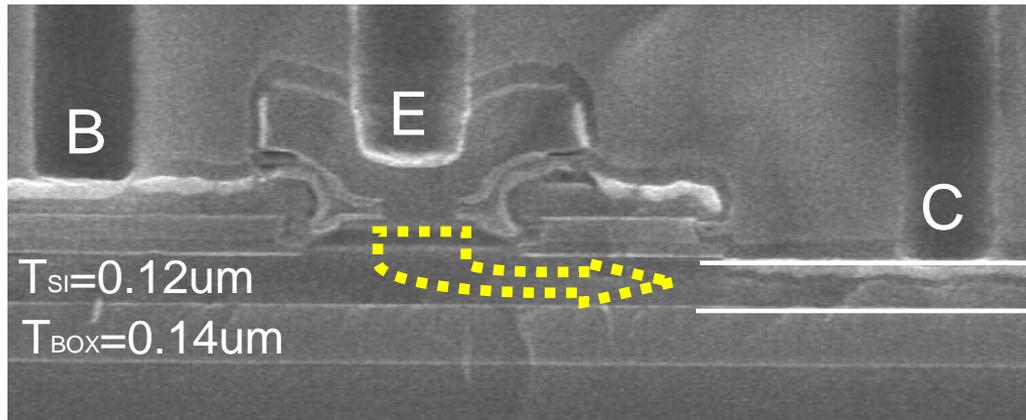


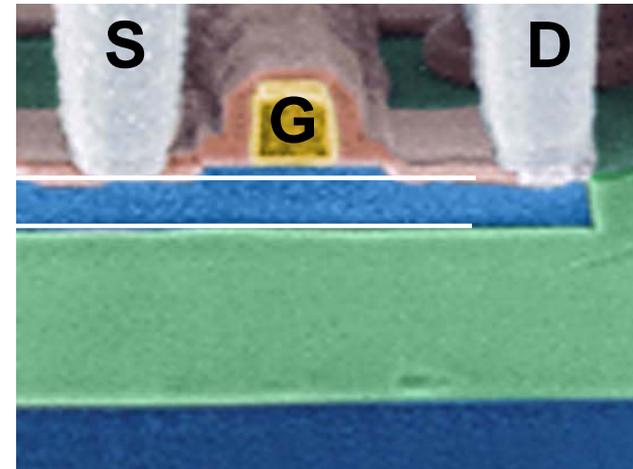
Fig. 3. (A) TEM x-section of LVC MOS. (B) TEM of HBT

Reference: J. Babcock et. al., 2010 BCTM

## Vertical SiGe-Base Bipolar on CMOS-Compatible SOI



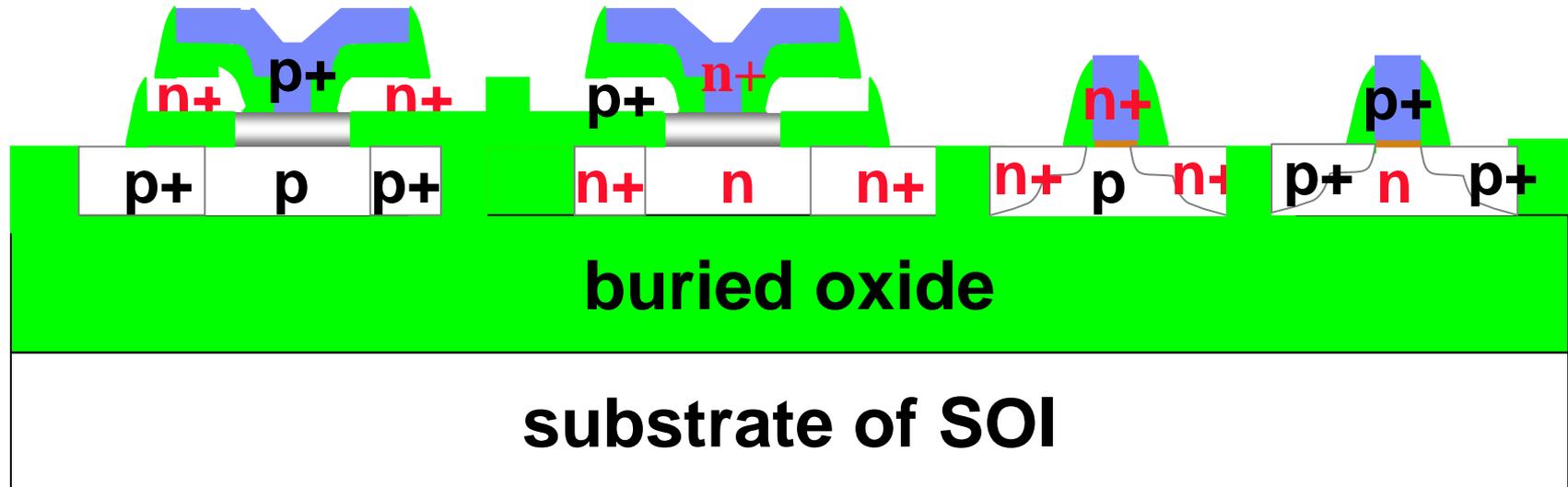
Thin-SOI **vertical** SiGe-base bipolar



SOI CMOS

Source: J. Cai et al., 2003 BCTM

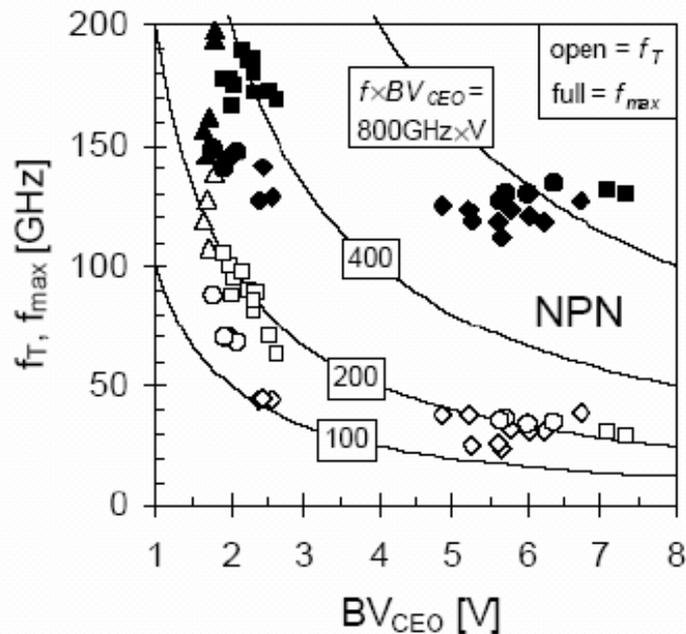
# Thin-SOI Complementary BiCMOS



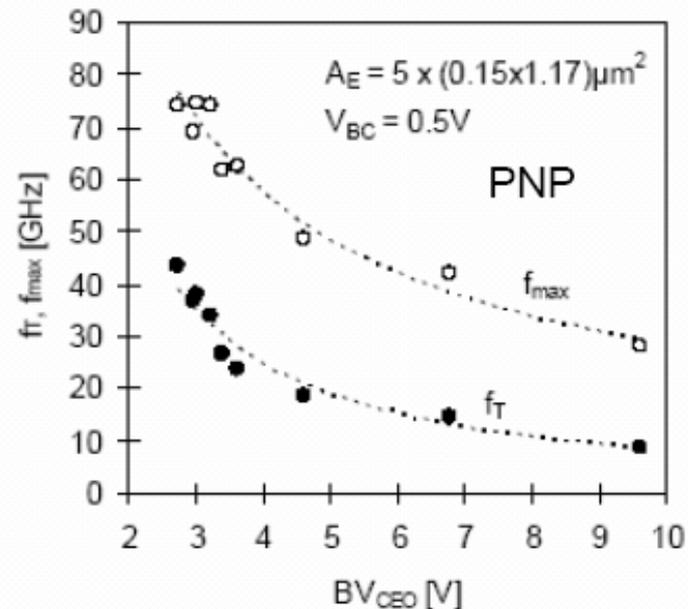
- **Vertical** npn and pnp, and CMOS on same thin SOI
- Opportunity for circuit innovation

Source: T.H. Ning, Symp. VLSI Technology, 2003

# Bipolar on thin SOI – FOM



A. Chantre et al, ECS – SiGe, 2006



J. Duvernay et al, BCTM 07

- First integration of both NPN and PNP **vertical bipolar devices in a thin SOI film** (160nm SOI over 400nm buried oxide) with high  $BV_{CE0}$  and  $f_T$ ,  $f_{max}$  has been demonstrated recently

- This integration is fully compatible with a 130nm SOI CMOS process

# The Problem with SOI CMOS

- **Cost, cost, cost**
  - SOI substrate cost
  - What else?
- **However, we need to consider**
  - Cost at the system level
  - Cost-benefit tradeoff
  - System-level benefit enabled by SOI

# Summary

- SoC and hybrid integration are natural trends in integrated-circuit technology
- SOI CMOS provides an ideal platform for SoC and hybrid integration
  - Electrical isolation
  - SOI-unique beneficial device and circuit characteristics
- In considering SOI versus bulk silicon CMOS as platform, need to bear in mind **cost-benefit tradeoff**
  - Additional benefit must be well worth the additional cost
- With innovation, the ***silicon technology glass remains half full***